

Optical Conductivity of Two-Dimensional Silicon: Evidence of Dirac Electrodynamics

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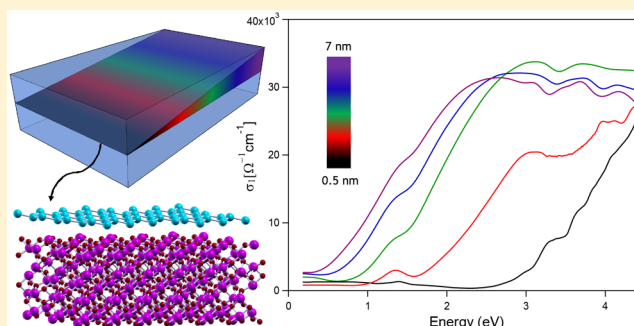
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Supporting Information

ABSTRACT: The exotic electrodynamics properties of graphene come from the linearly dispersive electronic bands that host massless Dirac electrons. A similar behavior was predicted to manifest in freestanding silicene, the silicon counterpart of graphene, thereby envisaging a new route for silicon photonics. However, the access to silicene exploitation in photonics was hindered so far by the use of optically inappropriate substrates in experimentally realized silicene. Here we report on the optical conductivity of silicon nanosheets epitaxially grown on optically transparent $\text{Al}_2\text{O}_3(0001)$ from a thickness of a few tens of nanometers down to the extreme two-dimensional (2D) limit. When a 2D regime is approached, a Dirac-like electrodynamics can be deduced from the observation of a low-energy optical conductivity feature owing to a silicene-based interfacing to the substrate.

KEYWORDS: Two-dimensional, silicon, silicene, $\text{Al}_2\text{O}_3(0001)$, optical conductivity, DFT calculations



Since its rise, graphene has been fostering unprecedented advances in a number of multidisciplinary applications.¹ A ubiquitous exploitation of graphene is limited by integration issues in many nanotechnology branches that are still based on silicon. Nowadays, silicon still offers the unique potential to cointegrate electronics and photonics at the nanoscale on a single chip.² Reducing silicon to a graphene-like form would bring a substantial technology throughput in this framework. The recently discovered two-dimensional (2D) allotropic phase of silicon, namely, silicene, followed up by other X-enes (X belongs to groups IIIA, IVA, and VA) renewed the interest in silicon-based nanomaterials as candidates for applications in nanotechnology.^{3,4} In fact, dimensional reduction of silicon opens new and intriguing routes for silicon nanoelectronics and photonics, like engineered and tunable in-gap absorption for photovoltaic application. Hitherto, most of the published reports are related to silicene growth on metallic templates, e.g., Ag(111); hence, these substrates cannot be easily used to directly access the optical properties of silicene and, more generally, of most of the X-enes sharing the same issue.⁵ Nonetheless, even the optical properties of silicene, as well as the electronic ones, are predicted to closely resemble those of the forerunning graphene. In particular, ideal freestanding silicene shares with

graphene the low-frequency electrodynamics, characterized by a universal absorption value $\pi\alpha$, where α is the fine-structure constant.^{6–8} Intriguingly, the rise of massless Dirac fermions at low-energy occurs despite either the buckling amount or the mixed sp^2 – sp^3 hybridization.⁶ For higher energy, the theoretical absorbance spectrum of freestanding silicene is characterized by two main interband transitions at M ($\pi \rightarrow \pi^*$ transition, hereafter termed I) and Γ ($\sigma \rightarrow \sigma^*$ transition, termed II) points of the first Brillouin zone (BZ) at 1.6 and 4 eV, respectively, corresponding to van Hove singularities of the joint density of states (JDOS).^{6–8} Nonetheless, when silicene is supported by a metallic substrate, most of these properties vanish as far as spurious hybridization come into play. For instance, for the silicene on Ag(111) case, the strong Si–Ag hybridization has been proven to deeply affect the electronic and optical properties of the supported silicene,^{9,10} giving rise to a complicated absorbance spectrum showing superimposition of different contributions with mixed Si–Ag

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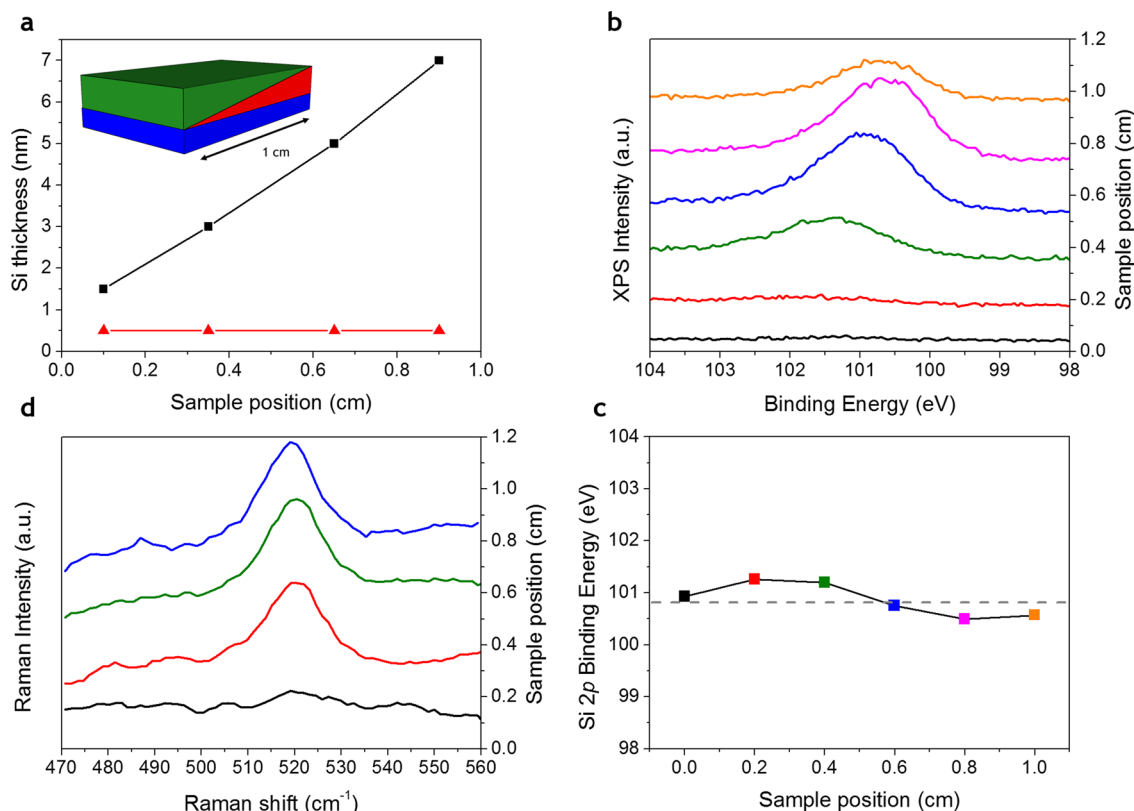


Figure 1. (a) SiNSs thickness by AFM for the VT sample (black dots, line is a guide for the eye) and the CT sample (red triangles). Inset displays schematics of the Al₂O₃-capped (green) VT sample showing the increasing silicon thickness (red) along one Al₂O₃(0001) substrate (blue) direction. (b) XPS spectra and (c) binding energy of the Si 2p core level along the increasing silicon thickness of the VT sample, where the gray dashed line is the average value (black line is a guide for the eye). (d) Raman spectroscopy of the first-order mode along the increasing thickness direction as for (b).

68 and Ag–Ag transitions.¹¹ In this light, many efforts should be
 69 then devoted to the synthesis of silicene or, generally speaking,
 70 of low-dimensional silicon nanosheets (SiNSs), on dielectric
 71 (transparent) substrates in order to reduce the interaction, pro-
 72 viding a more ideal case to investigate silicene optical prop-
 73 erties and therein enabling silicene-based photonics. In this
 74 framework, Al₂O₃(0001), with a reported experimental bandgap
 75 of 8.8 eV,¹² has been recently proposed as a commensurate
 76 substrate either for silicene or for germanene epitaxy.¹³ Indeed,
 77 on the basis of first-principles calculations, Chen et al. suggested
 78 that the Al-terminated surface of Al₂O₃(0001) can stabilize a
 79 monolayer honeycomb structure of silicene (also germanene)
 80 without destroying the Dirac states, because the substrate,
 81 being a large-gap semiconductor with a proper work function,
 82 imposes the Dirac point to lie in the gap and far from the sub-
 83 strate states when their bands align. Silicene on Al₂O₃(0001)
 84 retains the main structural profile of the low-buckled honey-
 85 comb lattice.¹³ Stimulated by this theoretical prediction, here we
 86 report on the innovative synthesis of SiNSs on Al₂O₃(0001)
 87 substrates by molecular beam epitaxy (MBE), under carefully
 88 tailored conditions, and on the related optical response from
 89 infrared (IR) to ultraviolet (UV). The first time measured
 90 optical conductivity shows a low-energy electrodynamics behavior
 91 in agreement with a Dirac-like electronic dispersion. This experi-
 92 mental result is further corroborated and critically interpreted
 93 by density functional theory (DFT) *ab initio* calculations of the
 94 structural, electronic, and optical properties based on a silicene
 95 model. Our outcomes demonstrate that, at the pure 2D limit,

SiNSs grown on Al₂O₃(0001) retain the properties of free- 96
 standing silicene in their optical conductivity. 97

In order to get through the optical properties of silicene at 98
 the 2D limit, three main issues should be first addressed, i.e., 99
 silicon growth, precise thickness determination, and integrity 100
 and stability of specifically designed samples. Hence, we studied 101
 samples with different SiNSs thicknesses down to 0.5 nm 102
 (see [Methods](#)) on the ultrahigh vacuum (UHV) prepared 103
 Al₂O₃(0001) surface, which is Al-terminated.^{14,15} However, to 104
 take into account substrate-induced effects on the optical mea- 105
 surements, we fabricated a specific type of sample with variable 106
 silicon thickness, which ranges from 1.5 to 7 nm through 1 cm 107
 wide Al₂O₃ substrate, as well as a constant thickness (CT) 108
 (0.5 nm) sample at the pure 2D limit ([Figure 1a](#)). 109

The former one is deemed to illustrate the optical behavior 110
 of the increasing silicon thickness of which the latter is the 111
 lower limit. A 25 nm thick amorphous sample was further 112
 grown at room temperature with the same MBE technique, as 113
 reference for comparison. Precise control on the SiNSs thick- 114
 ness is confirmed through an *ex situ* atomic force microscopy 115
 (AFM) survey (see [Figure 1a](#) and Supporting Information 116
[Figures S1–S3](#)) and plays a crucial role for the optical prop- 117
 erties. The variable thickness (VT) SiNS sample allowed us to 118
 access the properties of the SiNSs avoiding background issues 119
 related to substrate variability and it is schematically depicted 120
 in the inset of [Figure 1a](#). *In situ* X-ray photoelectron spec- 121
 troscopy (XPS) was carried out along the slope of the VT 122
 sample to check the chemical status of the SiNSs after the 123
 growth. [Figure 1b](#) shows that the Si 2p core level is placed on 124

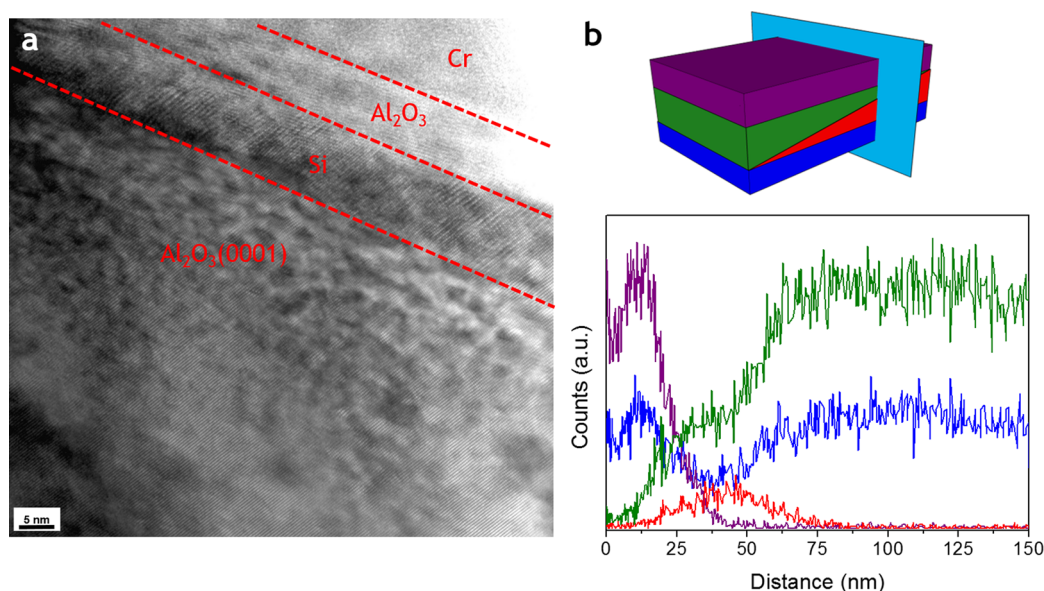


Figure 2. (a) TEM image of the cross-section view (from top to bottom) of the Cr/a-Al₂O₃/Si/Al₂O₃(0001) stack. (b) Sketch of the stacking cross sectional cut (top) and EDX line scans of K_{α1} of chromium (purple), aluminum (green), silicon (red), and oxygen (blue) (bottom) extracted from the respective maps reported in Figure S4.

average at 100.89 eV, thus resulting in a moderate shift to higher binding energy than that of silicene on Ag(111),¹⁶ on MoS₂(0002),¹⁷ and on ZrB₂(0001).¹⁸ Figure 1c indicates there is a small variation in binding energy along the thickness slope (within the experimental error of ± 0.08 eV), with a higher binding energy for the thinner part of the VT sample, i.e., for the SiNSs in close contact with the substrate. Furthermore, the observed shift of the silicon core level to higher binding energy is strictly related to the low-dimensionality of the SiNSs, as demonstrated by its thickness-dependent behavior (Figure 1c), which refers to the change in the (size-dependent) ionization potential.¹⁹ Indeed, a similar binding energy (100.73 eV) is found even in the thinnest CT investigated sample (see Supporting Information Figure S2). However, the binding energy of bulk silicon (~ 99 eV) is almost recovered for the ~ 25 nm thick amorphous sample (see Supporting Information Figure S3), in good agreement with the optical measurements (see below).

In order to prevent the oxidation when samples are taken out of UHV environment, SiNSs were encapsulated with a 5 nm thick Al₂O₃ amorphous capping layer (see Methods and ref 16). After capping, the Si 2p core level shifts to lower binding energy (99.54 eV). This shift is likely related to charge transfer between silicon and amorphous oxide at the interface, as reported for silicene on Ag(111),¹⁶ rather than chemical modifications within the SiNSs. Indeed, no signatures of silicon oxides have been disclosed throughout the XPS analysis and this is also confirmed by the unchanged full width half-maximum values of the Al 2p and O 1s core levels before and after silicon deposition (Supporting Information Table S1). Moreover, this amorphous capping layer does not affect the optical properties of SiNSs on Al₂O₃(0001), due to its small thickness and intrinsic transparency. Hence, top and bottom interfaces of SiNSs are protected by transparent films. Accordingly, the Raman scattering investigation depicted in Figure 1d shows the first-order Raman mode of the encapsulated SiNSs at different spatial positions along the thickness slope of the VT sample. At each position, a clear Raman feature is observed at ~ 520.5 cm⁻¹, close to the F_{2g} mode of cubic silicon at 520.6 cm⁻¹

(or equivalently of thin silicon-on-insulator films),²⁰ thus confirming the presence of the SiNSs even after the encapsulation process and the subsequent exposure of the samples to ambient condition. Furthermore, the increase of the Raman mode intensity as a function of the spatial position (along the direction shown in the inset of Figure 1a) confirms the thickness variation along the slope in agreement with the AFM and XPS measurements. The low intensity of the Raman mode in the thinnest part of the VT sample (black spectrum in Figure 1d) can be likely related to the small Raman scattering efficiency for the encapsulated SiNSs at the used laser frequency. This similarly occurs on the CT sample. These Raman modes were successfully recovered even months after the growth, without hints of amorphous or deteriorated silicon, thus confirming the stability of the encapsulated SiNSs in ambient conditions. Combining XPS and Raman spectroscopy, the effectiveness of the Al₂O₃ capping layer to durably protect 2D silicon on substrates other than Ag(111) is demonstrated. It is not surprising to find a Raman mode placed so close to those of bulk Si(111) and silicene on Ag(111), as far as the predicted Si-Si bond length l in silicene on Al₂O₃(0001) ($2.34 < l < 2.37$ Å; see also Supporting Information) is very close to those of bulk Si(111) (2.34 Å) or silicene on Ag(111) ($2.28 < l < 2.39$ Å).²¹ Additional evidence on the SiNSs growth is provided by transmission electron microscopy (TEM) imaging that shows the formation of a continuous crystalline silicon film sandwiched between the amorphous Al₂O₃ capping layer and the Al₂O₃(0001) substrate (Figure 2a).

Higher-resolution TEM images are hampered by the well-known issue on the electron beam-induced crystallization of the amorphous Al₂O₃,²² with a progressive deterioration of the whole lamella in a few seconds. However, the SiNSs in the thicker part of the VT sample (see cross-section cut in Figure 2b) are clearly confined without any chemical intermixing between the substrate and the capping layer, as evidenced by the energy dispersive X-rays (EDX) analysis (Figure 2b), thus suggesting a chemically protected environment for the SiNSs. Line profiles of the corresponding EDX maps (reported in Supporting

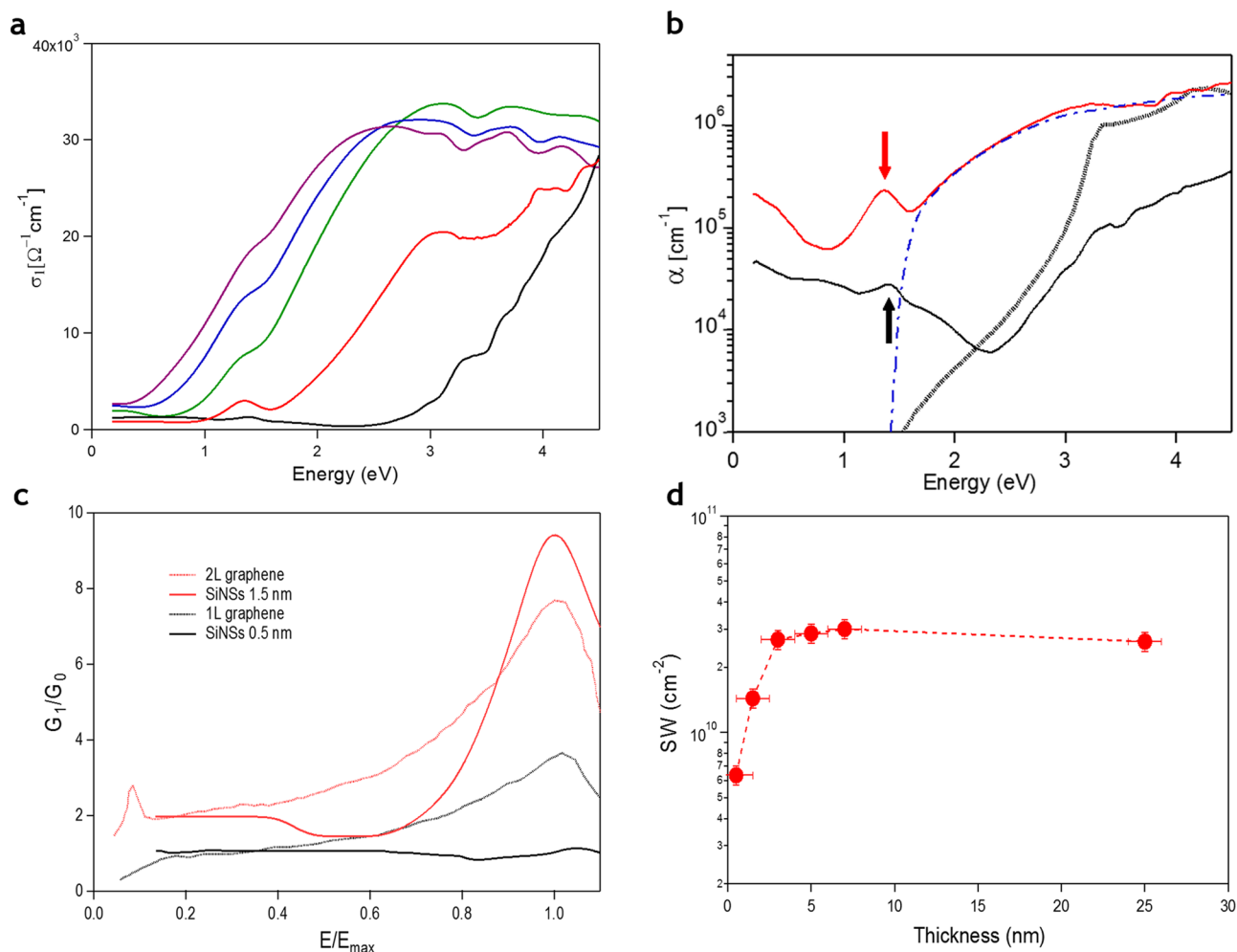


Figure 3. (a) Real part of the optical conductivity $\sigma_1(\omega)$ for the five thickness scrutinized: 0.5 (black), 1.5 (red), 3 (green), 5 (blue), and 7 nm (purple). (b) The absorption coefficient $\alpha(\omega)$ for the 0.5 and 1.5 nm thick film (black and red curves), of the 25 nm thick bulk reference (dashed-dotted blue line) and that of crystalline bulk silicon (dashed gray line). Black and red arrows point out the transition I for 0.5 and 1.5 nm, respectively. At 25 nm, one nearly recovers the bulk properties of 3D silicon. (c) Real part of the optical conductance $G_1(\omega)$ normalized to the universal optical conductance G_0 for the 0.5 (black line) and 1.5 nm (red line) thickness SiNSs. In order to properly compare these spectra with those of single layer (black dotted line) and two layers (red dotted line) graphene, the frequency axis is normalized to the bonding–antibonding π transition appearing around 1.4 eV in SiNSs and around 4.6 eV in graphene.²³ (d) SW calculated from $\omega_m = 0.25$ to $\omega_M = 4.5$ eV for the five thicknesses scrutinized in a and reference 25 nm thick sample (red dashed line is a guide for the eye).

Information Figure S4) show that the silicon signal (red curve) is maximum where both aluminum (green curve) and oxygen (blue curve) have a (local) minimum intensity. The absolute optical transmittance $T(\omega)$ (Supporting Information) was measured on CT (0.5 nm), VT (from 1.5 to 7 nm), 25 nm “bulk” samples, and the bare $\text{Al}_2\text{O}_3(0001)$ substrate, in the photon frequency (ω) range from IR (0.25 eV) to UV (4.5 eV). It is worth noting that outside this energy range and in particular in the mid-IR range below 0.25 eV, $\text{Al}_2\text{O}_3(0001)$ strongly absorbs, thereby preventing a reliable transmittance measurement of SiNSs films. From the knowledge of the real and the imaginary parts of the refractive index of $\text{Al}_2\text{O}_3(0001)$ substrate (determined from its absolute transmittance and shown in Supporting Information Figure S5) and of $T(\omega)$ of SiNSs, we have determined the optical conductivity $\sigma(\omega) = \sigma_1(\omega) + i\sigma_2(\omega)$ of SiNSs through the use of a Kramers–Kronig constrained fit (see Methods and Supporting Information). Figure 3a shows the real part of the optical conductivity for different thicknesses. $\sigma_1(\omega)$ at the lowest thickness (CT sample, 0.5 nm, black curve in Figure 3a) shows a

small absorption peak around 1.4 eV superimposed to a nearly flat background in the whole IR range.

In the visible spectral range, $\sigma_1(\omega)$ drops with a broad gap and rises linearly around 3 eV up to the UV range. Interestingly, the spectral feature around 1.4 eV and the increasing absorption around 4 eV, closely resemble those arising from I and II interband transitions in freestanding silicene by *ab initio* calculation.^{6–8} When the SiNS thickness is increased to 1.5 nm (red curve in Figure 3a), $\sigma_1(\omega)$ is still nearly flat below 1 eV, the absorption peak around 1.4 eV is now very well-defined and the linearly increasing absorption starts around 2 eV. A close inspection of Figure 3a clearly evidences that the absorption feature around 1.4 eV is reminiscent of the calculated peak I appearing at about 1.6 eV in the freestanding silicene (see below).^{6–8} For a further increase of the thickness, one observes a softening and broadening of the UV absorption that progressively superimposes to the peak around 1.4 eV. The flat absorption region, although still visible up to the maximum thickness of 7 nm, is more and more reduced to the low-frequency part of the conductivity spectrum. In order to investigate the

241 evolution of the optical properties of SiNSs samples with
242 thickness and to recover the expected optical behavior of bulk
243 silicon, Figure 3b compares the absorption coefficients $\alpha(\omega)$ of
244 the 0.5 and 1.5 nm thick SiNSs (black and red curves), of the
245 reference amorphous 25 nm thick sample (blue dashed-dotted
246 curve), and of bulk crystalline silicon (dashed-line black curve).²⁴
247 At first glance, we notice that the optical behavior of SiNSs
248 strikingly deviates from that of a bulk silicon whose absorption
249 is partially restored only for the thickness of 25 nm with a well-
250 defined band gap around 1.3 eV. The finite absorption in the
251 IR region is therefore strongly indicative of an exotic electronic
252 structure reminiscent of the massless Dirac fermions. Although
253 not as direct evidence as provided by other experimental
254 techniques, e.g., angle-resolved photoelectron spectroscopy, we
255 notice the sensitivity of the optical conductivity is inherently
256 related to the JDOS, thus bringing reliable evidence of the
257 electronic structure of the SiNSs. Indeed, similar to graphene,
258 the optical conductivity over the corresponding spectral range
259 can be demonstrated to be a robust quantity.²⁵ In particular, all
260 the $\sigma_1(\omega)$ spectra reported here (up to 7 nm thick SiNSs)
261 markedly differ not only from the absorbance spectrum of
262 cubic diamond bulk silicon but also from that of silicite (the
263 surmised silicon counterpart of graphite), or other reported
264 silicon allotropes.^{26–28} Nonetheless, such a different behavior
265 can be explained by the stabilization of a 2D hexagonal phase
266 of silicon in the early stage of the epitaxy on the $\text{Al}_2\text{O}_3(0001)$
267 substrate, which consequently affects the subsequent three-
268 dimensional (3D) growth regime. This argument is further
269 corroborated by the comparison with graphene. Figure 3c
270 shows the low-frequency behavior of SiNSs (0.5 and 1.5 nm
271 thick), described in terms of the real part of the optical
272 conductance $G_1(\omega)$. This quantity, which is related to the optical
273 conductivity through the equation $G_1(\omega) = \sigma_1(\omega) \cdot d$, where d is
274 the film thickness, is conventionally used to describe the
275 optical properties of 2D materials like graphene²⁵ and topo-
276 logical insulators.^{29,30} In Figure 3c $G_1(\omega)$ is derived and then
277 normalized to the universal conductance $G_0 \equiv e^2/4\hbar$,³¹ which
278 is an intrinsic property of 2D massless electrons as experi-
279 mentally measured in graphene and confirmed by theoretical
280 predictions.^{23,32} Moreover, in order to facilitate the compar-
281 ison with graphene, a universal frequency axis is obtained by
282 normalizing the actual frequency with respect to the bonding–
283 antibonding π transition appearing around 1.4 eV in SiNSs and
284 around 4.6 eV in graphene, respectively.²³ As observed in
285 Figure 3c, G_1/G_0 below 1 eV saturates (as a flat background)
286 to the universal values 1 and 2 for $d = 0.5$ and 1.5 nm, respec-
287 tively. This is in good agreement with measurements reported
288 on the one- and two-layer graphene (see for instance ref 23)
289 and represented in the same figure by black- and red-dotted
290 curves, respectively. The normalized optical conductance spectra
291 of SiNSs in the lowest photon energies look comparatively
292 flatter than those of graphene due to the absence of doping
293 (sample-dependent) issues.²⁵ This universal scaling behavior,
294 i.e., an integer value of universal conductance as a function of
295 the layer thickness, is a characteristic hallmark of 2D Dirac
296 fermions in graphene and suggests that 2D silicon grown on a
297 $\text{Al}_2\text{O}_3(0001)$ substrate retains the properties of freestanding
298 silicene, whose low-energy electrostatics is related to a
299 linear (Dirac-like) electronic dispersion. Furthermore, by com-
300 parison with graphene (Figure 3c), we can speculate that 0.5
301 and 1.5 nm thick SiNSs may be regarded as if they were single-
302 and double-layer silicene, respectively. Additional experimental

and theoretical efforts are therefore highly demanded to
unravel this surmise.

Finally, we study the redistribution of the optical spectral
weight (SW) using the f -sum rule analysis. Figure 3d shows the
experimental $\text{SW} = \frac{120}{\pi} \int_{\omega_m}^{\omega_M} \sigma_1(\omega) d\omega$ for a frequency range
between $\omega_m = 0.25$ and $\omega_M = 4.5$ eV for all the SiNSs
thicknesses considered. The SW plot exhibits a 2-fold fashion,
namely, a steep monotonic increase with thickness up to ~ 3 nm
and then a nearly flat behavior for thicker SiNSs, with saturation
at ~ 25 nm (amorphous silicon reference), indicative of a
2D-to-3D crossover. Although other measurements are necessary
to elucidate the transition from 2D silicene-like to 3D silicon-like
optical behavior, the thickness range here considered can offer
great potential for applications beyond the state-of-the-art on
IR–visible photonics and optoelectronics based on dimen-
sionally reduced silicon, where a unique benefit is gained from
silicon being sandwiched between the transparent substrate
and capping layer.

Although the experimental data for the thinnest SiNSs
surveyed show a fair agreement with the theoretical predictions
of freestanding silicene, it is demanding to unravel the role of
the $\text{Al}_2\text{O}_3(0001)$ substrate, in consideration of the strong influ-
ence of the substrate in the optical properties of other silicene
systems, e.g., silicene supported by $\text{Ag}(111)$.¹¹ Moreover, the
observed experimental data are apparently not compatible
with the calculated electronic bandstructure of the supported
silicene proposed by Chen et al., which actually reveals that the
Dirac cone disappears, and just a vague reminiscence of it
survives at the K point of the BZ with a bandgap of 0.44 eV.¹³
Hence, in order to elucidate the experimental scenario, we
performed *ab initio* calculations of the structural, electronic,
and optical properties of silicene on $\text{Al}_2\text{O}_3(0001)$, thus focusing
on the comparison with the thinnest (CT) SiNS. We theo-
retically deposit a single layer of silicon atoms on the surface,
exploring different possible adsorption geometries (see Support-
ing Information Figures S7 and S8). The $\text{Al}_2\text{O}_3(0001)$ surface
periodicity is 3×3 with respect to the clean one, whereas
the silicon overlayer's periodicity becomes $\sqrt{13} \times \sqrt{13} R_{13.9^\circ}$
with respect to the ideal freestanding silicene. The Born–
Oppenheimer energy surface of the so-composed system, i.e.,
silicene and $\text{Al}_2\text{O}_3(0001)$, presents many local minima. Several
different and metastable $\sqrt{13} \times \sqrt{13}$ silicene geometries on the
 3×3 $\text{Al}_2\text{O}_3(0001)$ substrate were indeed found in addition to
the structures modeled by Chen et al.¹³ Differences among
them rely on the mutual position of silicon and aluminum/
oxygen atoms. In all the cases, the silicene overlayer is sub-
jected to a strain of about 3.3% because of the lattice mismatch
with the substrate and also silicene loses its pristine D_{3d}
symmetry. Basically, all the studied geometries can be grouped
into two categories, where the subsystems $\text{Al}_2\text{O}_3(0001)$ and
silicene are either strongly interacting (with average distance
between the substrate and the overlayer of about 2.8 Å) or
weakly interacting (with an average distance of about 3.3 Å).
Table S2 summarizes the main properties of the two represen-
tative cases, the SIS (strongly interacting silicene, belonging to
the former group) and the WIS (weakly interacting silicene,
belonging to the latter group). The energy differences among
the reported geometries are small; hence, their coexistence is
possible even at room temperature. Even if the binding energy
is moderate, indicating a quite limited interaction with the
substrate, a gap as large as 0.44 eV opens at K point of BZ in
the case of the SIS configuration, in agreement with the results

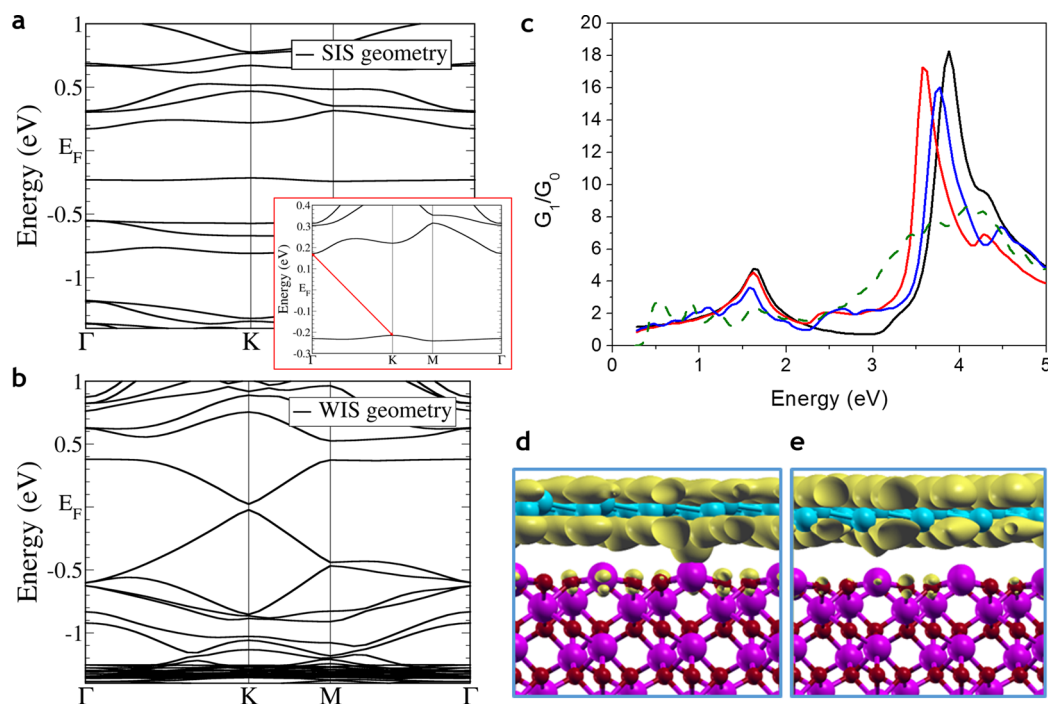


Figure 4. (a) Calculated electronic band structure for SIS geometry (inset shows zoom of the indirect bandgap) and (b) for the WIS geometry. (c) Normalized conductance G_1/G_0 for SIS (green dashed) and WIS (blue) on $\text{Al}_2\text{O}_3(0001)$ configurations. Corresponding quantities for ideal freestanding silicene (black) and for freestanding silicene with 3% strain (red) are also reported for comparison. (d) Squared modulus of the electronic wave functions at the highest occupied bands and (e) at the lowest unoccupied bands at the K point for the WIS configuration.

365 by Chen et al.¹³ The Dirac cone is affected being hardly identifiable, as shown in Figure 4a, where the calculated electronic
 366 band structure is reported in the BZ of the $\sqrt{13}\times\sqrt{13}$ lattice.
 367
 368 On the contrary, when the interaction is smaller, as in the
 369 WIS geometry, the Dirac cone still survives but the Dirac
 370 fermions become massive. In fact, as shown in Figure 4b, a
 371 small gap of about 0.05 eV opens at K point but a significant
 372 similarity with the linear band behavior of freestanding silicene
 373 close to the Fermi level still survives. In other words, the
 374 degree of interaction of the silicon overlayer with $\text{Al}_2\text{O}_3(0001)$
 375 tunes the electronic band structures which, as we will show in
 376 the following, have profound consequences on the low-energy
 377 part of optical spectra of the system. $\text{Al}_2\text{O}_3(0001)$ surface
 378 possesses a DFT gap of about 5 eV; hence, it is transparent in
 379 the energy range where instead ideal silicene absorbs. From the
 380 two representative geometries WIS and SIS, the optical prop-
 381 erties of silicene on $\text{Al}_2\text{O}_3(0001)$ have been calculated in terms
 382 of $G_1(\omega)$ (Figure 4c and Supporting Information) and com-
 383 pared to that of the ideal system. For the SIS investigated
 384 geometry the low-energy optical conductivity (green dashed
 385 line, Figure 4c) strongly differs from that of freestanding
 386 silicene (black line), due to the opening of a significant gap in
 387 the mid-IR (about 0.5 eV), which has not been observed in the
 388 experimental data, and a no discernible peak I. However, the
 389 WIS geometry (blue line) shows optical properties similar to
 390 those of ideal silicene and qualitatively comparable to the
 391 experimental data of the CT sample (Figure 3a). In particular,
 392 the WIS configuration still shows a discernible peak I slightly
 393 softened with respect to the freestanding silicene (the same
 394 softening trend has been observed experimentally) and a nearly
 395 flat conductivity below the peak I. Strain effects due to the lat-
 396 tice mismatch between silicene and $\text{Al}_2\text{O}_3(0001)$ in the weak-
 397 interacting configuration are responsible of the small shift in
 398 the peak II, which in the unstrained silicene (black curve in

Figure 4c) is at 3.9 eV (due to the interband $\sigma \rightarrow \sigma^*$ transition
 399 at Γ), in artificially strained freestanding silicene appears at
 400 3.6 eV (red curve), and in the WIS appears at 3.8 eV (blue
 401 line). Also, the spectrum in the energy region between 2.2 and
 402 3.0 eV clearly shows similarities with the strained freestanding
 403 silicene. Peak I around 1.6 eV is almost unaffected by the
 404 presence of the substrate and by the strain and is very close to
 405 the experimentally observed one. At lower energies, the nor-
 406 malized conductance G_1/G_0 of the WIS structure, still related
 407 to low-energy $\pi \rightarrow \pi^*$ transitions but close to K point, tends to
 408 1 as occurs for ideal silicene and the CT sample (Figure 3c).
 409 The squared modulus of the wave function at the K point for
 410 the highest occupied band (Figure 4d) and the lowest unoc-
 411 cupied band (Figure 4e) are essentially due to silicon, indicating
 412 that silicon is atomically bonded to but almost electronically
 413 decoupled from the substrate. Although the WIS structure
 414 significantly helps to understand the conductivity spectrum
 415 of the supported silicene on $\text{Al}_2\text{O}_3(0001)$, especially in com-
 416 parison with the experimental data of SiNSs at the 2D limit on
 417 the same substrate, it is not clear yet why the WIS should set
 418 in instead of the other energetically competing configuration.
 419 Bearing in mind that the energy difference between the SIS
 420 and WIS structures is not large, a possible argument for the
 421 stabilization of the latter relies on the high-temperature growth
 422 condition (670 °C, see Methods) as promoter for the growth
 423 of a silicene configuration with a relatively lower stability.
 424 By and large, we speculate that as much as the interaction
 425 between (reconstructed) silicene and $\text{Al}_2\text{O}_3(0001)$ is relaxed,
 426 the theoretical electronic and optical descriptions turn out to
 427 improve the agreement with the experimental data. Our work
 428 is anyway demanding for further specific investigation devoted
 429 to understand the possible presence of a buffer layer decreasing
 430 the interaction between silicon and substrate, and to further
 431

432 explore the manifold configurations in which SiNSs may accommodate on $\text{Al}_2\text{O}_3(0001)$.

434 Summarizing, we investigated the optical properties of silicon at the 2D limit on $\text{Al}_2\text{O}_3(0001)$ by fabricating and encapsulating specific SiNSs with spatially constant and variable thickness. In this way, a Dirac-like behavior is observed in the IR part of the optical conductivity spectra of the 2D SiNSs, thus suggesting the presence of Dirac fermions hosted by a silicene-like structure. This argument is supported by the following evidence. First, the observed $\sigma_1(\omega)$ of the CT sample shows an overall behavior similar to that expected from the ideal silicene with a clear $\pi \rightarrow \pi^*$ interband transition feature. Second, the quantized conductance depending on the silicon thickness further suggests that the SiNSs at the 2D limit possess silicene-like properties, as already proved for graphene. Third, this experimental scenario is consistent with the *ab initio* model of a $\sqrt{13} \times \sqrt{13}$ structured silicene that is weakly interacting with the substrate. The identification of a Dirac-like optical conductivity peaked in the near-IR regime from a 2D silicon grown on an optical transparent substrate opens unexplored avenues in establishing a silicene-based photonics. In perspective, the proposed methodology can be further extended to other (also heavier) X-enes, paving the way to the exploitation of their exotic properties related to the nontrivial topology for applications in the optoelectronics and photonics fields, especially for the silicon case, in light of the well-known long lasting expertise on the silicon on sapphire to provide reliable multifunctional devices.

460 **Methods.** SiNSs were grown in a UHV chamber (base pressure 10^{-10} mbar) system equipped with interconnected chambers for sample growth via MBE and chemical analysis via XPS. Several hours of degassing at 250°C was performed on the single side polished $\text{Al}_2\text{O}_3(0001)$ samples (Crystec) before silicon growth. SiNSs were deposited from a heated crucible in the built-in evaporator or from a piece of silicon wafer with a rate of ~ 1 nm/h at a substrate temperature of 670°C and compared with a reference ~ 25 nm thick amorphous sample grown at room temperature. Temperature reading was cross-checked by pyrometer-based calibration of the thermocouple attached under the sample holder, and the deposition rate was confirmed *ex situ* by means of AFM thickness measurements. AFM investigations were performed *ex situ* on the capped samples by means of an AFM-Bruker system operating in tapping mode and equipped with an ultrasharp silicon probe (tip diameter < 10 nm). XPS characterization was carried out by means of a nonmonochromatized Mg and Al $K\alpha$ sources (1253.6 and 1486.6 eV, respectively) at a takeoff angle of 37° . An adventitious C 1s binding energy at 285.0 eV was used as reference to calibrate the energy shift of core levels due to substrate-induced charging effects. An amorphous 5 nm thick Al_2O_3 capping layer was grown *in situ* through reactive codeposition.¹⁶ *Ex situ* Raman spectroscopy was performed by using a Renishaw Invia spectrometer equipped with the 2.54 eV/488 nm line of an Ar^+ laser line focused on the sample by a $100\times$ Leica objective (0.9 numerical aperture) providing a spot diameter of about $0.4\ \mu\text{m}$. The power at the sample was maintained below 5 mW in order to prevent laser-induced sample heating. All the measurements were carried out in a z-backscattering geometry. For the TEM studies, lamellae were covered with metal (chromium) deposition to protect them during the procedure and prepared using the focus ion beam. The lamella were cut by milling with 30 kV gallium ions and thinned down with subsequent steps of 30 and 5 kV ion milling and then

mechanically transferred to a copper TEM grid. Scanning TEM (STEM) analyses were conducted using an aberration-corrected TEM operated at 200 kV. For the chemical analysis, EDX measurements were carried out using the same microscope equipped with a $80\ \text{mm}^2$ EDX silicon drift detector. In addition to EDX, the cross-sectional uniformity of the SiNSs has also been verified by Raman spectroscopy and IR microscopy with sampling steps of 0.2 cm and $100\ \mu\text{m}$, respectively. In order to investigate the optical properties of SiNSs grown on $\text{Al}_2\text{O}_3(0001)$, we measured the absolute transmittance $T(\omega)$ on both types of samples, i.e., constant thickness (CT, 0.5 nm), variable thickness (VT, from 1.5 to 7 nm), and reference 25 nm thick amorphous film, in the frequency (ω) range from 0.25 to 4.5 eV by using a Michelson IFS66 V Bruker interferometer in the IR and a JASCO spectrometer in the visible/UV region. From the measured $T(\omega)$ (see Figure S6 of Supporting Information), we have derived the optical conductivity $\sigma(\omega) = \sigma_1(\omega) + i\sigma_2(\omega)$ of SiNSs through the use of the Reffit program by means of Kramers–Kronig transformations, which takes into account the stratified structure of samples.³³ $\sigma_1(\omega)$ has been obtained by considering the actual complex refractive index of $\text{Al}_2\text{O}_3(0001)$ as determined from its absolute transmittance measured for a bare substrate coming from the same batch. The optical conductivity as extracted through Reffit from $T(\omega)$ by considering a two layers system (substrate and film) or three layers system (substrate, film, and amorphous capping layer) does not depend of the presence of the capping layer.

The electronic and optical properties of silicon on $\text{Al}_2\text{O}_3(0001)$ were calculated within *ab initio* DFT using norm-conserving pseudopotential with a Perdew–Burke–Ernzerhof exchange and correlation potential in the Quantum Espresso code.³⁴ The $\text{Al}_2\text{O}_3(0001)$ substrate was simulated with a symmetric slab made of 18 layers relaxed using $3 \times 3 \times 1$ k -points and an energy cutoff of 65 Ry. Silicene was added on the top $\text{Al}_2\text{O}_3(0001)$ surface and relaxed with the inclusion of van der Waals forces. A vacuum of 14 Å ensured that periodic images of the slab do not interact. Optical spectra were calculated within the single particle approximation (Fermi golden rule) using $18 \times 18 \times 1$ k -points for the $\sqrt{13} \times \sqrt{13} R13.9^\circ$ silicene on substrate and $400 \times 400 \times 1$ k -points for 1×1 freestanding silicene.

■ ASSOCIATED CONTENT

📄 Supporting Information

The Supporting Information is available free of charge on the ACS Publications website at DOI: 10.1021/acs.nanolett.8b03169.

Additional sample characterization data on VT, CT, and amorphous reference samples (Figures S1, S2, and S3 of AFM line profiles), XPS data (Table S1), EDX maps (Figure S4), real and imaginary parts of the $\text{Al}_2\text{O}_3(0001)$ refraction index (Figure S5), optical transmittance of SiNSs (Figure S6), structural models of SIS and WIS configurations (Figures S7 and S8) and their properties (Table S2), and supporting text on the calculation of the optical properties (PDF)

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557 Author Contributions

558 C.G. developed the epitaxial growth of the SiNSs samples and
559 subsequent Al₂O₃ encapsulation. C.G. also performed XPS
560 analysis. C.M. conducted Raman spectroscopy and AFM
561 studies of all the samples. P.T. and D.G. carried out TEM and
562 EDX investigations. SD and S.L. performed and elaborated
563 transmittance measurements. O.P. and P.G. carried out the
564 theoretical investigation and related electronic and optical
565 models. C.G., A.M., and S.L. planned the experiments. All
566 authors contributed to the writing based on the draft written by
567 C.G. A.M. and S.L. coordinated and supervised the research.

568 Notes

569 The authors declare no competing financial interest.

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